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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use as many sheets as necessary)

Complete if Known

Application Number 10/671,116
 Filing Date 9/24/03
 First Named Inventor Schiek, Richard
 Art Unit 2825
 Examiner Name LIN, SUN JAMZE
 Attorney Docket Number SD-7173

Sheet 1 of 2**U. S. PATENT DOCUMENTS**

Examiner Initials*	Cite No. ¹	Document Number Number-Kind Code ² (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
<u>JS</u>		US- 5,903,099	05-11-1999	Johnson et al.	
		US- 6,074,890	06-13-2000	Yao et al.	
		US- 6,082,208	07-04-2000	Rodgers et al.	
		US- 6,277,666 B1	08-21-2001	Hays et al.	
		US- 6,563,106 B1	05-13-2003	Bowers et al.	
		US- 6,567,715 B1	05-20-2003	Sinclair et al.	
		US- 6,574,033 B1	06-03-2003	Chui et al.	
		US- 2002/0086456 A1	07-04-2002	Cunningham et al.	
		US- 2003/0021523 A1	01-30-2003	De Natale	
		US- 2003/0062332 A1	04-03-2003	Harris et al.	
<u>JS</u>		US- 2003/0060051 A1	03-27-2003	Kretschmann et al.	
		US-			
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FOREIGN PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Foreign Patent Document Country Code ³ Number ⁴ Kind Code ⁵ (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages Or Relevant Figures Appear	T ⁶

Examiner
SignatureJames Sun JinDate
Considered10-19-05

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. ¹ Applicant's unique citation designation number (optional). ² See Kinds Codes of USPTO Patent Documents at www.uspto.gov or MPEP 901.04. ³ Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵ Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁶ Applicant is to place a check mark here if English language translation is attached.

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		Art Unit	2825
		Examiner Name	LIN, SUN JAMES
Sheet 2	of 2	Attorney Docket Number	SD-7173

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
JSR		SUNGWOOK, CHO, Development of a Geometry-Based Process Planning System for Surface Micromachining, International Journal of Production Research, 2002, Vol. 40/No. 5/MAR, pp. 1275-1293, Institution of Production Engineers.	
JSR		R. SCHIEK and R. SCHMIDT, A New, Topolog Driven Method for Automatic Mask Generation from Three-Dimensional Models, Feb. 23, 2003, Sandia National Laboratory, Computational Sciences Department, Albuquerque, New Mexico.	
JSR		THE NATIONAL ACADEMY OF SCIENCES, 2 Integrated Circuit Based Fabrication Technologies and Materials, Microelectromechanical Systems: Advanced Materials and Fabrication Methods (1997), pp. 14-22, http://www.nap.edu/openbook/0309059801/html .	

Examiner Signature	<i>James Sun</i>	Date Considered	10-19-05
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